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Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 29089/39605	Serial No. 10. 662604
		Applicant Fracheboud et al.	
		Filing Date 9/15/03	Group 2859

INFORMATION DISCLOSURE STATEMENT

U.S. PATENT DOCUMENTS							
*Examiner Initials		Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
26		3,869,799	03/11/75	Neuer et al.	33	174 L	
		4,964,223	10/23/90	Linder et al.	33	556	
		5,005,297	04/09/91	Aehnelt et al.	33	559	
		5,029,398	07/09/91	Ertl	33	503	
26		6,453,566	09/24/02	Bottinelli et al.	33	1M	12/22/00

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*Examiner Initials		Document Number	Publication Date	Country	Class	Subclass	Translation	
							Yes	No
26		102 744 B1	03/14/84	EPO				
		1 013 949 A1	06/28/00	EPO			Abstract only	
		1 113 191 A2	07/04/01	EPO			Abstract only	
26		37 15 698 A1	12/01/88	Germany			Abstract only	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
26	"Accuracy Limitations of Fast Mechanical Probing", van Vliet et al., Eindhoven University of Technology, Section Precision Engineering, Eindhoven, The Netherlands, January 8, 1996, pp. 483 - 487
26	"Development of a 2D Probing System With Nanometer Resolution", Pril et al., Eindhoven University of Technology, Eindhoven, The Netherlands, American Society for Precision Engineering, Proceedings Volume 16, 1997, pp. 438-442
26	"Design for a Compact High-Accuracy CMM", Peggs et al., Center for Length Metrology, National Physical Laboratory, Teddington, Middlesex, UK, January 8, 1999, pp. 417-420
26	European Search Report in EP 02 020 887.2 dated March 17, 2003

Examiner G. Bradley Bennett	Date Considered 12 JUL 2004
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	